



Image AF/1763  
PATENT  
Atty. Dkt. No. AMAT/6493/ETCH/SILICON/JB

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
Nallan, et al.

Serial No.: 09/993,240

Confirmation No.: 6869

Filed: November 13, 2001

For: Apparatus for Controlling a  
Thermal Conductivity Profile for  
a Pedestal in a Semiconductor  
Wafer Processing Chamber

**MAIL STOP AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

## RESPONSE TO FINAL OFFICE ACTION DATED NOVEMBER 20, 2003

In response to the Final Office Action dated November 20, 2003, having a shortened statutory period for response set to expire on February 20, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/6493/AOP, \$140.00 for excess claim fees, and any additional amount for other fees, including extension of time fees, required to make this response timely and acceptable to the Office.

Amendments to the claims are reflected in the listing of claims which begins on page 2 of this paper. Remarks begin on page 7 of this paper.

01/30/2004 MAHMEDI 00000060 200782 09993240

01 FC:1201 86.00 DA  
02 FC:1202 54.00 DA

CERTIFICATE OF MAILING  
37 CFR 1.8

I hereby certify that this correspondence is being deposited on Jan. 20, 2004, with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Jan. 20, 2014 ari hancock  
Date Signature